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Bib Data Sheet

SERIAL NUMBER 09/991,166	FILING DATE 11/16/2001 RULE	CLASS 438	GROUP ART UNIT 1765	ATTORNEY DOCKET NO. 05630 USA P 01/ETCH/METAL
APPLICANTS Chentsau Ying, Cupertino, CA; Jeng H. Hwang, Cupertino, CA; Yong Deuk Ko, Kyonggi, KOREA, REPUBLIC OF; Se Jin Oh, Suwon, KOREA, REPUBLIC OF; Chan Ouk Jung, Seoul, KOREA, REPUBLIC OF;				
** CONTINUING DATA ***** This application is a CIP of 09/918,671 07/27/2001 PAT 6,770,567				
** FOREIGN APPLICATIONS ***** REPUBLIC OF KOREA 10-2001-40309 07/06/2001				
IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** 12/03/2001				
Foreign Priority claimed 35 USC 119 (a-d) conditions met Verified and Acknowledged	<input type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance Examiner's Signature _____ Initials _____	STATE OR COUNTRY CA	SHEETS DRAWING 6	TOTAL CLAIMS 60
				INDEPENDENT CLAIMS 7
ADDRESS 32588 APPLIED MATERIALS, INC. 2881 SCOTT BLVD. M/S 2061 SANTA CLARA , CA 95050				
TITLE METHOD OF REDUCING PARTICULATES IN A PLASMA ETCH CHAMBER DURING A METAL ETCH PROCESS				
		<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees (Filing)		